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PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 2823**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Seiichi MIYAZAKI

Group Art Unit: 2823

Application No.: 09/913,334

Examiner: G. Fourson

Filed: August 13, 2001

Docket No.: 110386

For: ETCHANT, ETCHING METHOD AND SEMICONDUCTOR SILICON WAFER

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the June 8, 2004 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims;

Remarks.

*Please
enter
9/17/04*

*AF
EFW*